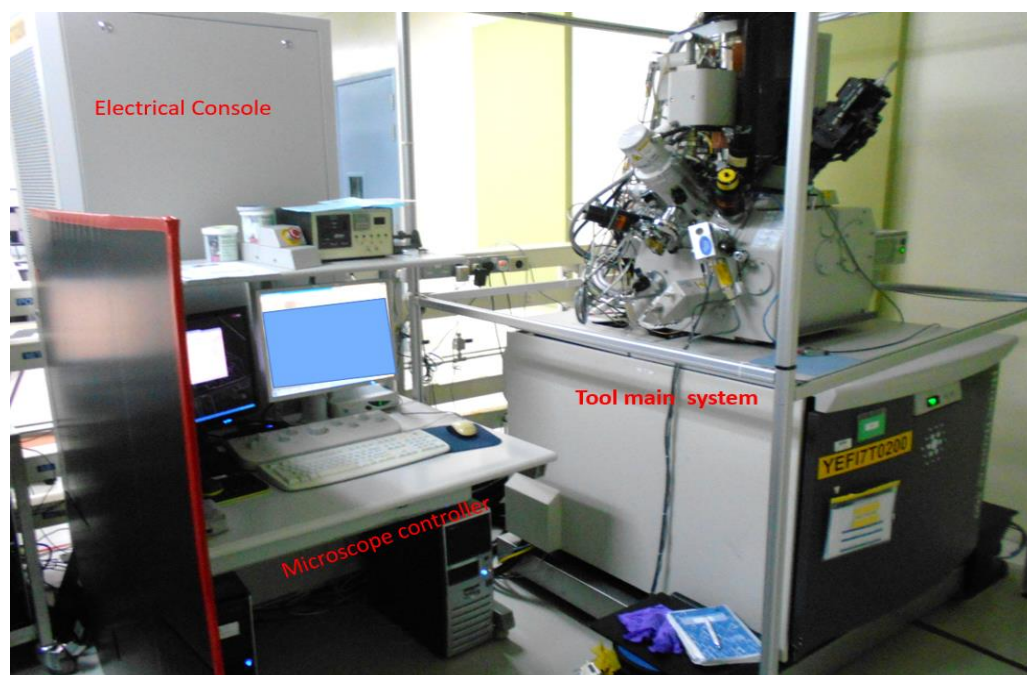
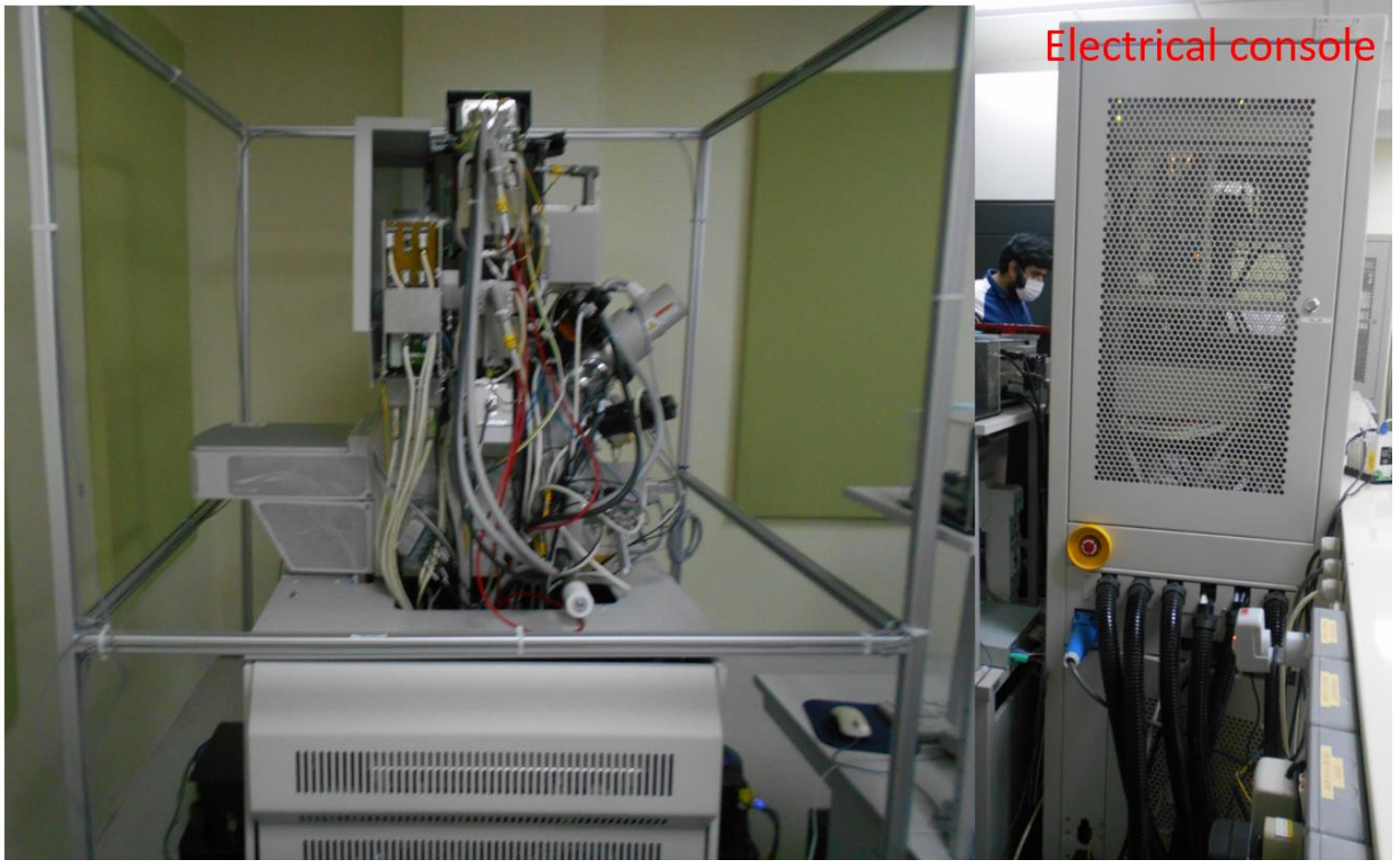


## FEI Helios Nanolab 400 Dual Beam FIB

- HELIOS Nanolab DB FIB
- System SW Version: xT3.8.8
- Microscope controller PC
- Support computer
- Monitor
- Switch box
- KEYBOARD
- MOUSE
- Electrical Console
- Neslab ThermoFlex 900 Chiller
- Edwards XDS 35 Vacuum Pump
- No Omniprobe Included
- Evactron 10 Plasma Cleaner
- 190-240VAC, Single phase, 50/60Hz



Micron Tool ID	Micap # Yefi7t0200	AGSS / Adelis Tool ID	RMMT20139
Manufacturer	FEI Company	Model	Helios Nanolab 400
Serial Number	D5031	Process	Failure Analysis
Vintage	2007	Wafer Size	N/A
Current Status	Installed until Sept. 2020	Location	Singapore



# EQUIPMENT DATASHEET



Chiller



Pump



Evactron 10 Plasma Cleaner

